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Express Mail No.: EL 452 481 927 US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Fuyuhiko Inoue

Serial No.: 09/960,585

Group Art Unit: 1756

Filed: September 21, 2001

Examiner: To be assigned

For: SWITCHING TYPE DUAL WAFER STAGE Attorney Docket No.: 10636-007-999

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Prior to examination of the above-identified patent application, please amend the application and drawings as follows:

In the Specification:

Marked up versions of all revised paragraphs, showing insertions and deletions, are included in Appendix A.

Replace the paragraph beginning on page 5, line 4 with:

Fig. 13(a) - (e) is a flowchart illustrating a method according to the present invention;

and

Replace the paragraph beginning on page 12, line 11 with:

Fig. 13(a) - (e) is a flowchart of a preferred method for utilizing the dual wafer stage of the present invention. This flowchart illustrates a preferred method of utilizing dual wafer stage assembly 40 of the present invention. The flowchart further illustrates interferometer use during the movement of the stages. Individual steps in the flowchart are discussed in more detail in the referenced sub-illustrations of Fig. 3 and Fig. 14(a) - (v).